DSSD, milestones and other mechanics

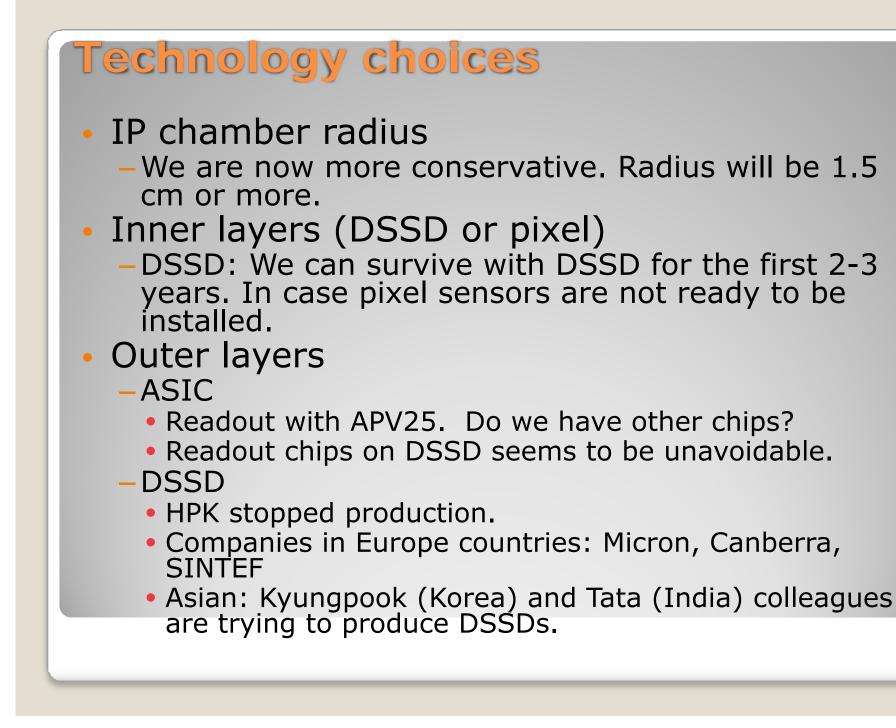
4 July 2008 T. Tsuboyama (KEK)

LOI design

- The LOI SVD design assumes DSSD sensors from HPK 4" line.
 - Unfortunately, HPK stopped the DSSD production.
- Alternative vendors
 - Micron → Several samples in hands: Not bad. Production from 6" wafers.
 - Kyungpook → DC coupled DSSD was produced. Test in progress.
 - Tata → Waiting for the first test production. Doublesided, double-metal and AC-coupled sensor prototype.

Test production by Micron?

- Sensors from 6" wafers are attractive in design of SVD.
- Need to fix the SVD design and DSSD sizes.

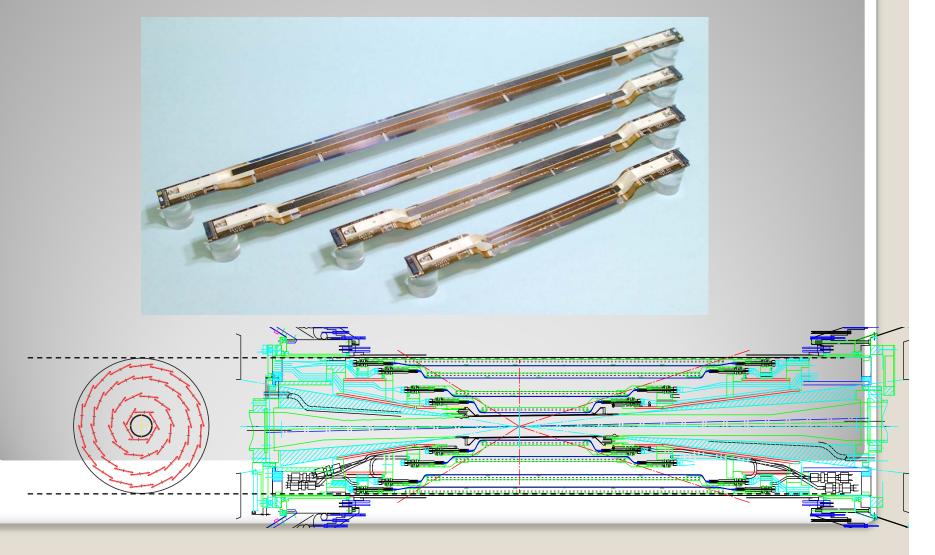


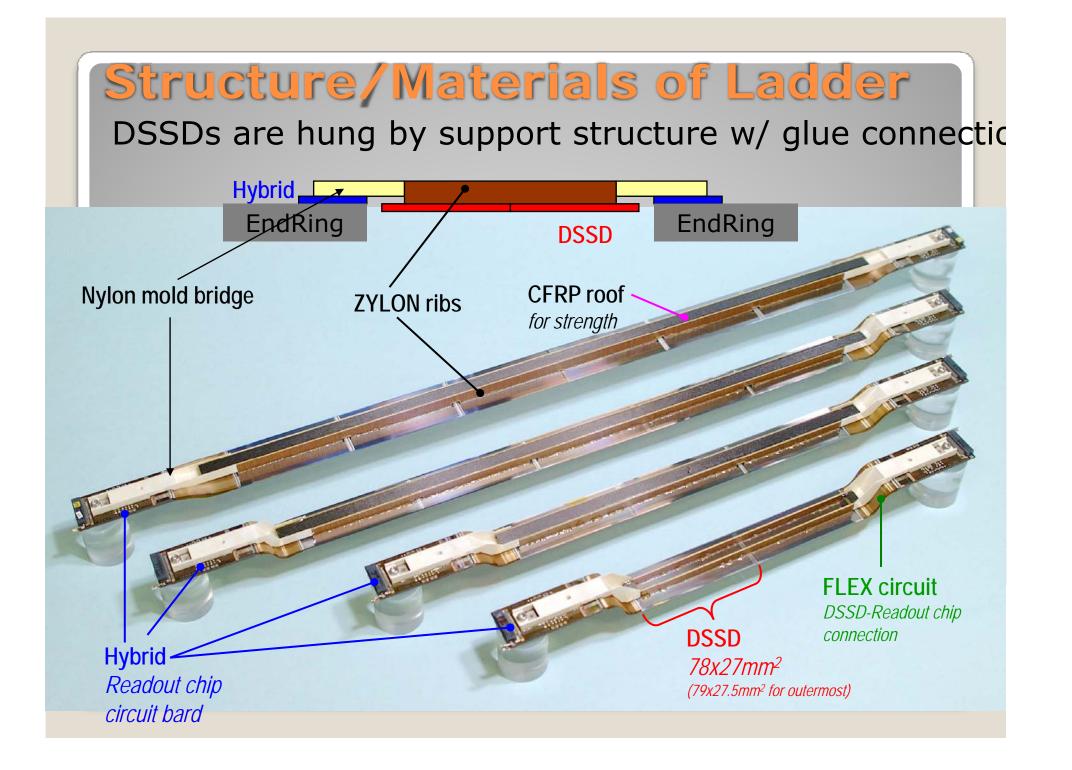
Milestones

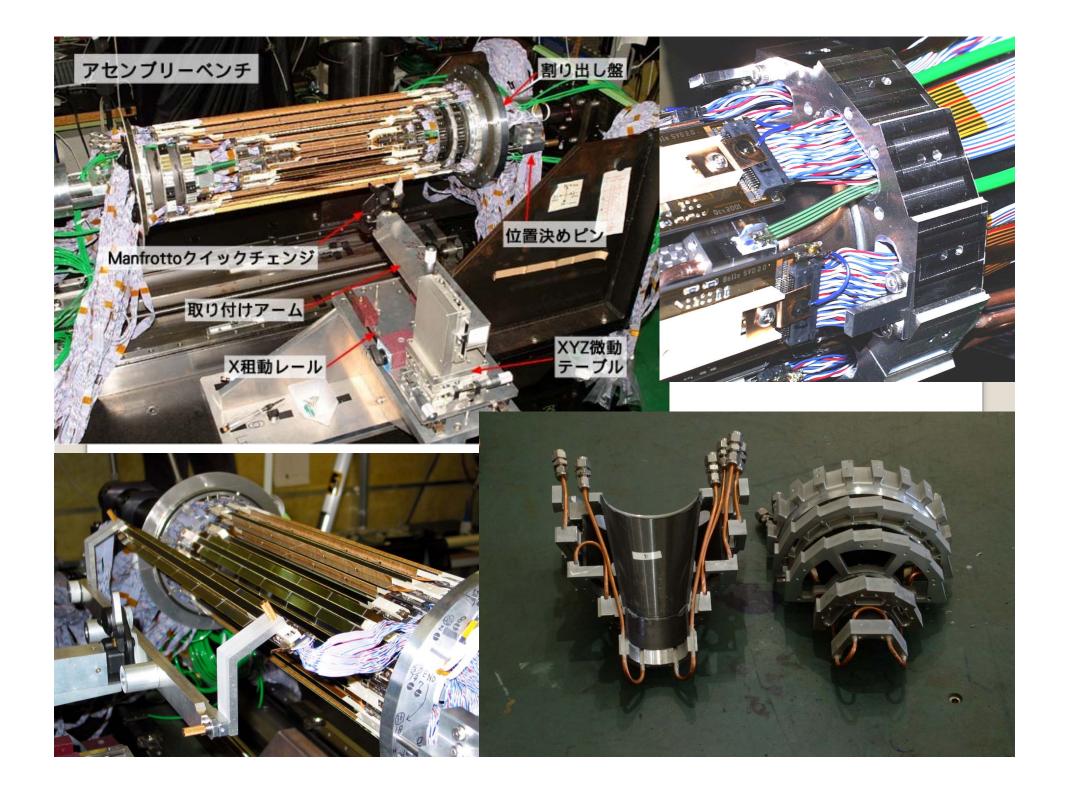
- 2008
 - Demonstrate APV25 readout chain.
 - Design optimization (Osaka, Niigata)
 - Vienna group: APV25 front end, repeater and FADC
 - Cracow group: Data acquisition board (COPPER/FINNESE)
 - DSSD test production
- 2009
 - Fix the design of Silicon vertex detector including pixel.

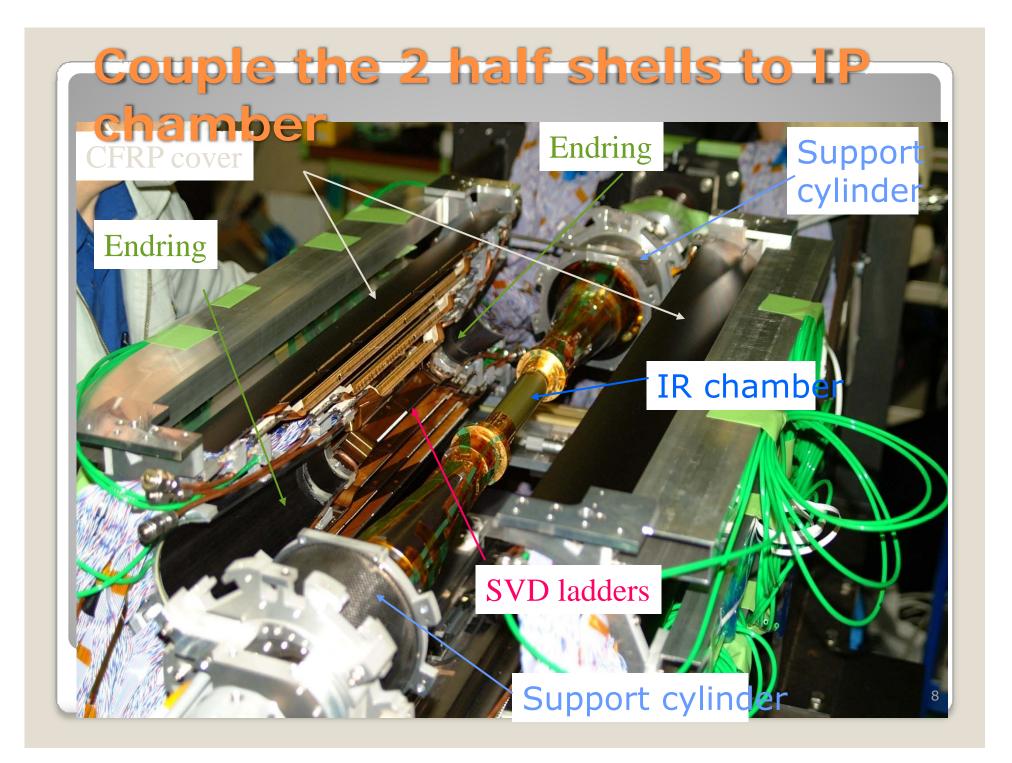
Ladder structure

Unit to realize layer structure using DSSDs



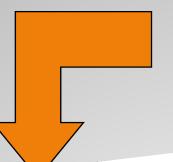




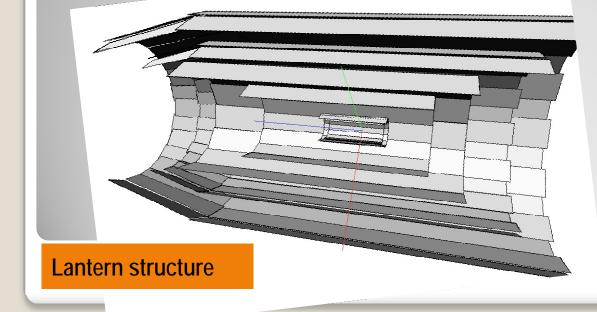


Ladder layout / mount

ladders were mounted on the endring







Innder four layers are mounted on endring ⇔

Outer two (super-) layers are mounted on the outer cover, then cover will be mounted on the endring

Mechanical consideration

 Can strips and pixels be separated?
Staging/replacement of Pixel detector sometime after the installation.

 What if pixel sensor is mounted on the IP chamber, while strips are mounted on support structure?

